IN THE UNITED STATES PATENT AND TRADEMARK OFFICE.

Applicant: Hongqin Shi Art Unit: 1792

Serial No.: 10/666,671 (8251) Examiner: Vinh, Lan

Filed: 17 September 2003 Docket No. TI-62961

For: METHODS AND APPARATUS OF ETCH PROCESS CONTROL IN

FABRICATIONS OF MICROSTRUCTURES

RESPONSE UNDER 37 C.F.R. § 1.111

23 February 2009

Commissioner for Patents P.O. Box 1450 Alexandria, Virginia 22313-1450

Dear Madam:

In response to the Examiner's Action dated 22 September 2008 applicant responds as follows: